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B₁~~ processing apparatus, of holding and transporting said one or more wafers, and of transferring said one or more wafers, via said duct, to said insertion portion of another wafer processing apparatus.

[(2) Please replace claim 12 with the following new claim 12 (APPENDIX 2):]

B₂ 12. (twice amended) A conveyance system in accordance with claim 10, wherein said position detecting element comprises a plurality of mobile element detecting sensors placed along said guide path, and said mobile element detecting sensors are placed at regular distance intervals throughout the guide path or placed at narrower intervals near the wafer processing apparatuses than along midways between adjacent two wafer processing apparatuses.

[(3) Please replace claim 13 with the following new claim 13 (APPENDIX 3):]

13. (twice amended) A conveyance system in accordance with claim 1, wherein the degree of air purity in said chamber is higher than the degree of purity outside said chamber.
